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I hereby certify that this paper and every
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09-27-2004 Shelly Hall
Date Name



FW

PATENT

Attorney Docket No.: 006915 P10
RW Ref. No.: APM/009-03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Dan MAYDAN, et al.

Serial No.: 10/786,410

Examiner: Unknown

Filed: February 24, 2004

Group Art Unit: 1763

For: FABRICATION OF SILICON-ON-INSULATOR STRUCTURE USING
PLASMA IMMERSION ION IMPLANTATION

PRELIMINARY AMENDMENT TRANSMITTAL

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S I R :

Transmitted herewith is a Preliminary Amendment in the above-identified application. The fee has been calculated as shown below.

	Claims remain- ing after amendment	Highest number previously paid for	Present extra	Rate	Additional Fee
Total Claims	59 minus	59 =	0	x \$18	\$000.00
Independent	2 minus	3 =	0	x \$86	\$000.00
If Multiple Dependent Claims Are Present, Add \$290.00					
(If applicant is a "small entity," subtract half of total)					\$000.00

Total additional fee
for this amendment \$000.00


☒ [X] No additional fee is required.

☐ [] A check in the amount of \$ is attached.

☒ [X] The Commissioner is hereby authorized to charge any additional fees or deficiencies or credit overpayment to Deposit Account No. 50-0338.

Respectfully submitted,

Dated: 9/24/08

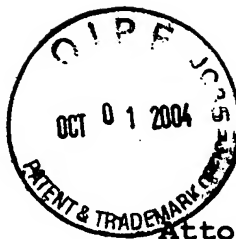

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Date Name



PATENT

Attorney Docket No. 006915 P10

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: :
Dan MAYDAN, et al. :
: Group Art Unit: 1763
Entitled: FABRICATION OF SILICON- :
ON-INSULATOR STRUCTURE USING PLASMA :
IMMERSION ION IMPLANTATION :
: Examiner: Unknown
Serial No.: 10/786,410 :
: :
Filing Date: February 24, 2004 :

PRELIMINARY AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to taking action in this case, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Amendments to the Drawings begin on page 18 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks begin on page 19 of this paper.

An **Appendix** including amended drawing figures is attached following page 19 of this paper.